

## Special Issue

# Development and Applications of Microwave/Millimeter Wave Diagnostics in Industry

### Message from the Guest Editors

The ever accelerating progress in microwave- and millimeter-wave devices and circuits, such as monolithic microwave integrated circuits (MMICs), and data processing including computer technology has contributed to the rapid advancement in diagnostic technology. This includes micro- to millimeter-wave imaging including optics imaging, synthetic imaging, and MIMO (multi-input multi-output) imaging. They have become of critical importance in various applications due to the possibility of high localization and accessibility of the measurements.

In this Special Issue, the scientific papers related to industrial applications of micro- to millimeter-wave diagnostics will be accepted, which include system development, data processing techniques, system application results, and physics understandings of the results. The potential applications may include the above-mentioned measurements. However, many valuable studies can be accepted for future advancements in this field.

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### Guest Editors

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### Deadline for manuscript submissions

closed (20 September 2022)



## Applied Sciences

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### Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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### Editor-in-Chief

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